

**Application Data Sheet****Application Information**

Application Type::	Regular
Subject Matter::	Utility
CD-ROM or CD-R:	None
Title::	METHOD FOR EVALUATING LITHOGRAPHY SYSTEM, METHOD FOR ADJUSTING SUBSTRATE-PROCESSING APPARATUS, LITHOGRAPHY SYSTEM, AND EXPOSURE APPARATUS
Attorney Docket Number::	109325.01
Suggested Drawing Figure::	
Total Drawing Sheets::	10
Small Entity::	No

**Applicant Information**

Applicant Authority type::	Inventor
Primary Citizenship Country::	Japan
Status::	Full Capacity
Given Name::	Yuji
Middle Name::	
Family Name::	IMAI
Name Suffix::	
City of Residence::	Saitama
State or Province of Residence::	
Country of Residence::	Japan

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**Correspondence Information**

Correspondence Customer Number:: 25944

<b>Domestic Priority Information</b>			
Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This Application is a	Division of	09/839,202	04/23/01
<b>Foreign Priority Information</b>			
Country::	Application Number::	Filing Date::	Priority Claimed::
Japan	2000-124506	04/25/00	Yes
<b>Assignee Information</b>			
Assignee Name::		NIKON CORPORATION	
Street of mailing address::		2-3, Marunouchi 3-chome	
		Chiyoda-ku	
City of mailing address::		Tokyo	
State or Province of mailing address::			
Country of mailing address::		Japan	
Postal or Zip Code of mailing address::		100-8331	